# Monthly LabAdviser/Process2Share update: 31/7 2015

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| Updated Subject | Contributor | Link to the updated pages |
| **New aligner: MA6\_2**  Inforamtion on this aligner has been added to LabAdviser | **Thomas Anhøj @danchip** | [UVExposure#Aligner:\_MA6\_-\_2](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/UVExposure#Aligner:_MA6_-_2) |
| **TiO2 with ALD**  More information on deposition of TiO2 with ALD has been added. | **Pernille V. Laresen**  **@danchip**  **Evgeniy Shkodin @Fotonik/Danchip** | [TiO2\_deposition\_using\_ALD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_Film_deposition/ALD/TiO2_deposition_using_ALD) |
| **IBE**  General tips for finding etching parameters | **Oxford Instruments, added by**  **Berit G. Herstrøm @danchip** | [IBSD\_Ionfab\_300/IBE\_process\_trends#General\_tips\_for\_finding\_etching\_parameters\_.28given\_by\_Oxford\_Instruments.29](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/IBE⁄IBSD_Ionfab_300/IBE_process_trends#General_tips_for_finding_etching_parameters_.28given_by_Oxford_Instruments.29) |
| **AFM Icon**  Evaluation of discarded ScanAsyst probes | **Berit G. Herstrøm @danchip** | [AFM:\_Atomic\_Force\_Microscopy/Workspaces#Evaluation\_of\_used\_probes](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/AFM:_Atomic_Force_Microscopy/Workspaces#Evaluation_of_used_probes) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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**Manual for Aligner: MA6 - 2**